



Attorney Docket No. SON-1745 Date: February 23, 2000

ASSISTANT COMMISSIONER FOR PATENTS Washington, D.C. 20231



Sir:

Transmitted herewith for filing is the patent application of

Inventor: Seiichi FUKUDA

For: DRY ETCHING METHOD AND METHOD OF MANUFACTURING

SEMICONDUCTOR APPARATUS

Enclosed are:

- \mathbf{X} Specification and Claim(s).
- \times Oath or Declaration
- \boxtimes six sheet(s) of drawings (2 sets)
- \boxtimes An assignment of the invention to Sony Corporation
- Copy of <u>one</u> priority application(s). X
- Associate Power of Attorney.

The fee has been calculated as shown below:

CLAIMS AS I	FILED	- Marie - 11 - 11 - 12 - 12 - 12 - 12 - 12 - 1		·= · · · · · · ·
FOR	NUMBER FILED	NUMBER EXTRA	RATE	BASIC FEE \$345/\$690
TOTAL			X \$ 9	
CLAIMS	8-20	0	\$18	:
INDEP.			X \$39	
CLAIMS	2-3	0	\$78	
Fee for Multiple Dependent Claims \$130/\$260				0
			TOTAL	
			FILING FEE	\$690

	A Preliminary Amendment is attached.	
	Verified Statement claiming small entity status is enclosed.	
X	Charge \$\frac{690.00}{1000}\$ to Deposit Account No. 18-0013 to cover the filing fee. A duplicate copy of this sheet is enclosed.	
X	The Commissioner is hereby authorized to charge any fees under 37 C.F.R. 1.16 or 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 18-0013. A duplicate copy of this sheet is enclosed.	
	A check in the amount of \$ over the filing fee is enclosed.	
	Charge \$ to Deposit Account No. 18-0013 to cover the recordal fee. A duplicate copy of this sheet is enclosed.	
X	Applicant's undersigned attorney may be reached by telephone in our Washington D.C. Office at	
	(202) 955-3750.	
All correspondence should be directed to our below listed address.		
	Ronald P. Kananen Reg. No. 24,104	

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